

H-Beam Cleaning of Metal Cathodes

David H. Dowell
SLAC & LCLS

Introduction

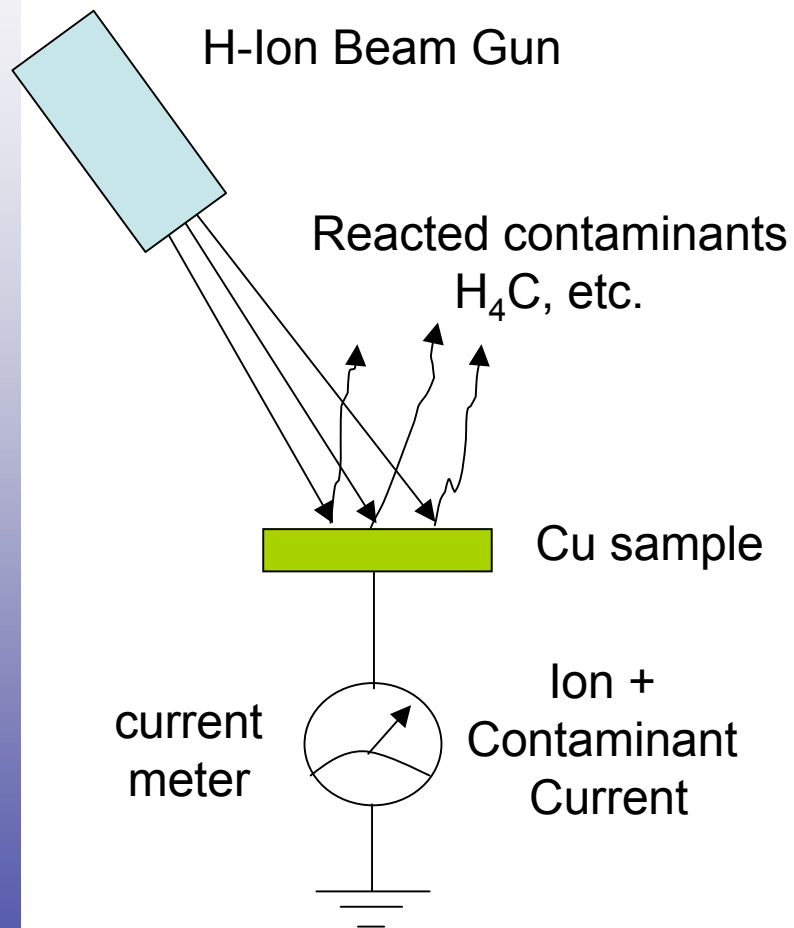
Cleaning and Measurement of Metal Cathodes

Extraction of Work Functions

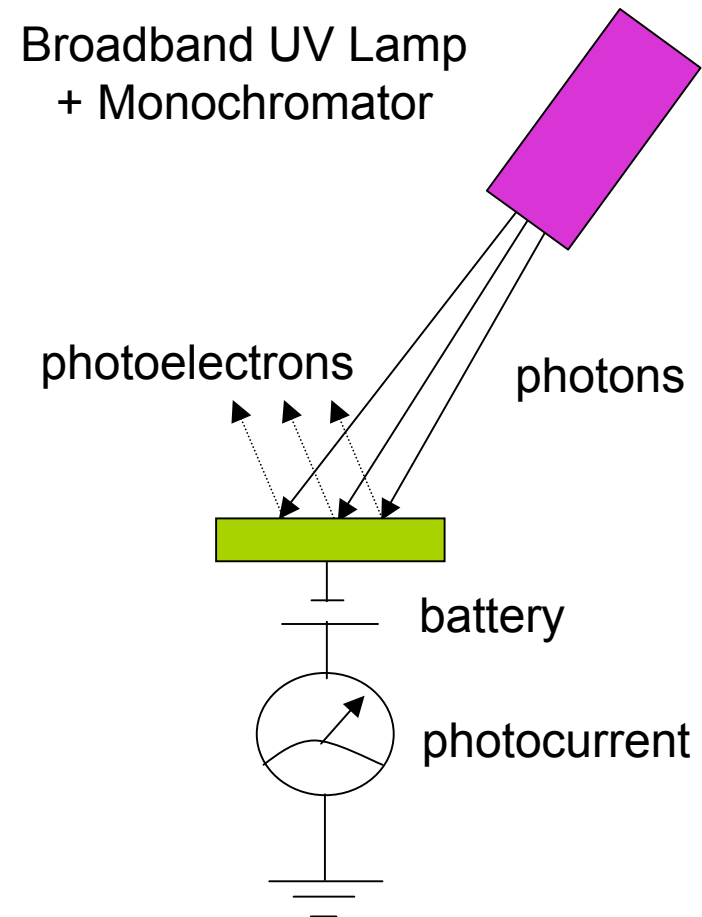
Comparison with Theory

Implementation into cathode processing and on gun

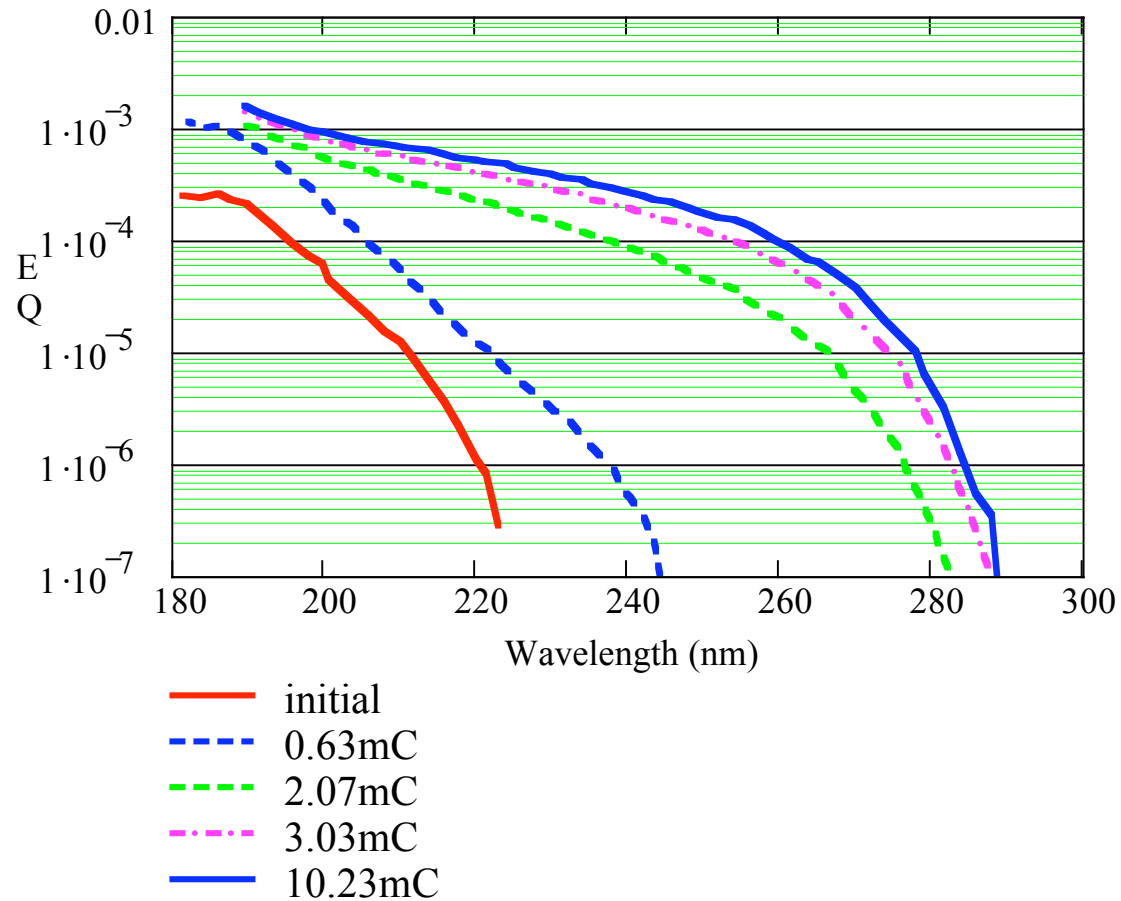
H-Beam Cleaning



QE vs. Wavelength Measurement



QE vs. Wavelength with Increased Exposed to H-Beam

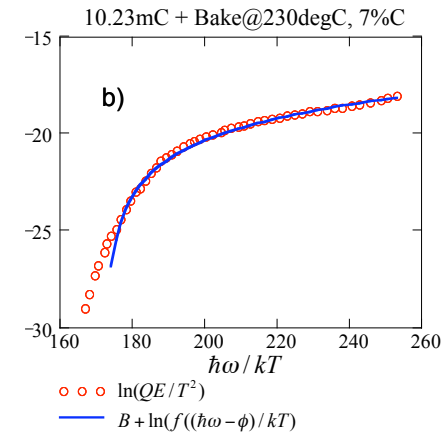
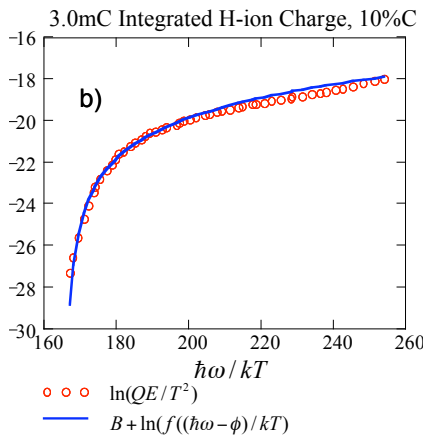
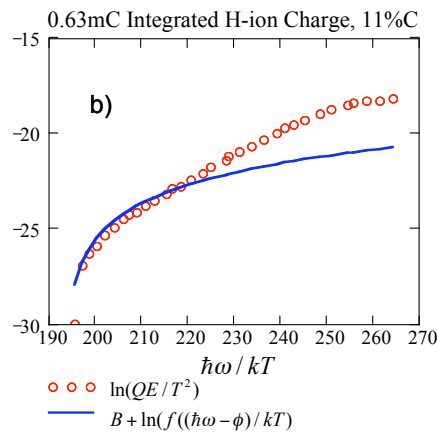
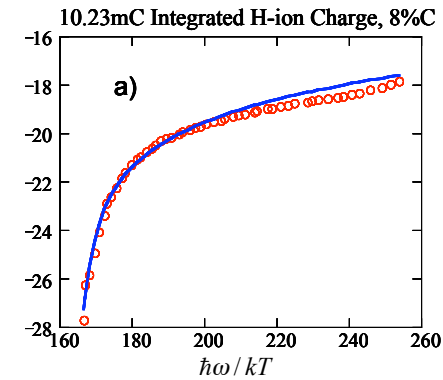
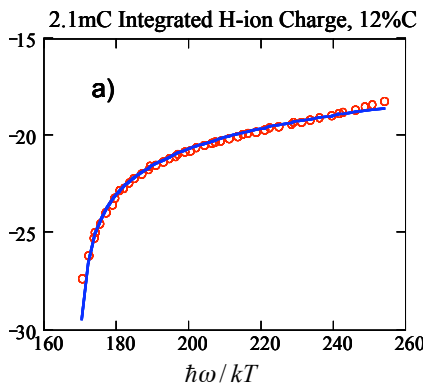
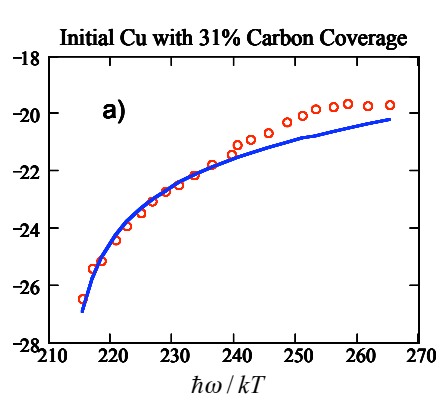


Fowler Plots with increasing H-ion Exposure

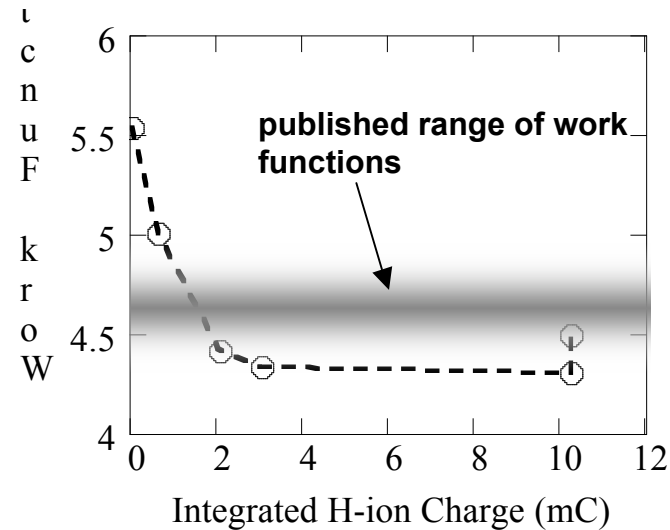
$$\ln\left(\frac{QE}{T^2}\right) = B + \ln\left(f\left(\frac{\hbar\omega - \phi}{kT}\right)\right)$$

$$f(x) = e^x - \frac{e^{2x}}{4} + \frac{e^{3x}}{9} - \dots \quad \text{for } x \leq 0$$

$$f(x) = \frac{\pi^2}{6} + \frac{x^2}{2} - \left(e^{-x} - \frac{e^{-2x}}{4} + \frac{e^{-3x}}{9} - \dots\right) \quad \text{for } x \geq 0$$



Work function vs. exposure to H-beam



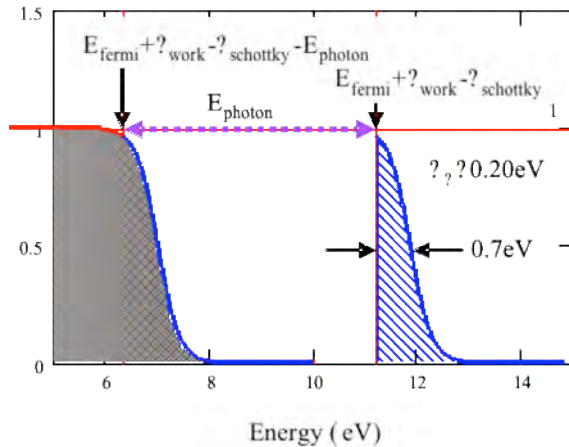
Theoretical Work Function:

3.9 eV: Hodges & Scott, Phys. Rev B7,73(1972)

4.1 eV: Lang & Kohn, Phys. Rev. B1,4555 (1970)

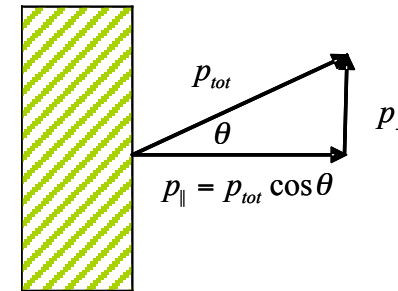
For a truly clean surface, the measured work function is in reasonable agreement with theory (~10-15% higher than theory)

Photoemission from a simple metal



$$\frac{p_{\parallel}^2}{2m} > E_{fermi} + \phi_{work} - \phi_{schottky}$$

$$\cos\theta_{max} = \sqrt{\frac{E_{fermi} + \phi_{work} - \phi_{schottky}}{E + \hbar\omega}}$$



Quantum Efficiency

$$QE = (1 - R) \frac{\int_{E_{vac}}^{E_{vac} + \phi_{work} - \phi_{schottky} - \hbar\omega} dE \int_{\cos\theta_{max}(E)}^1 d(\cos\theta) \int_0^{2\pi} d\phi \text{DOS}_{F-D}(E_{fermi}, E)}{\int_0^{E_{vac}} dE \int_0^1 d(\cos\theta) \int_0^{2\pi} d\phi \text{DOS}_{F-D}(E_{fermi}, E)}$$

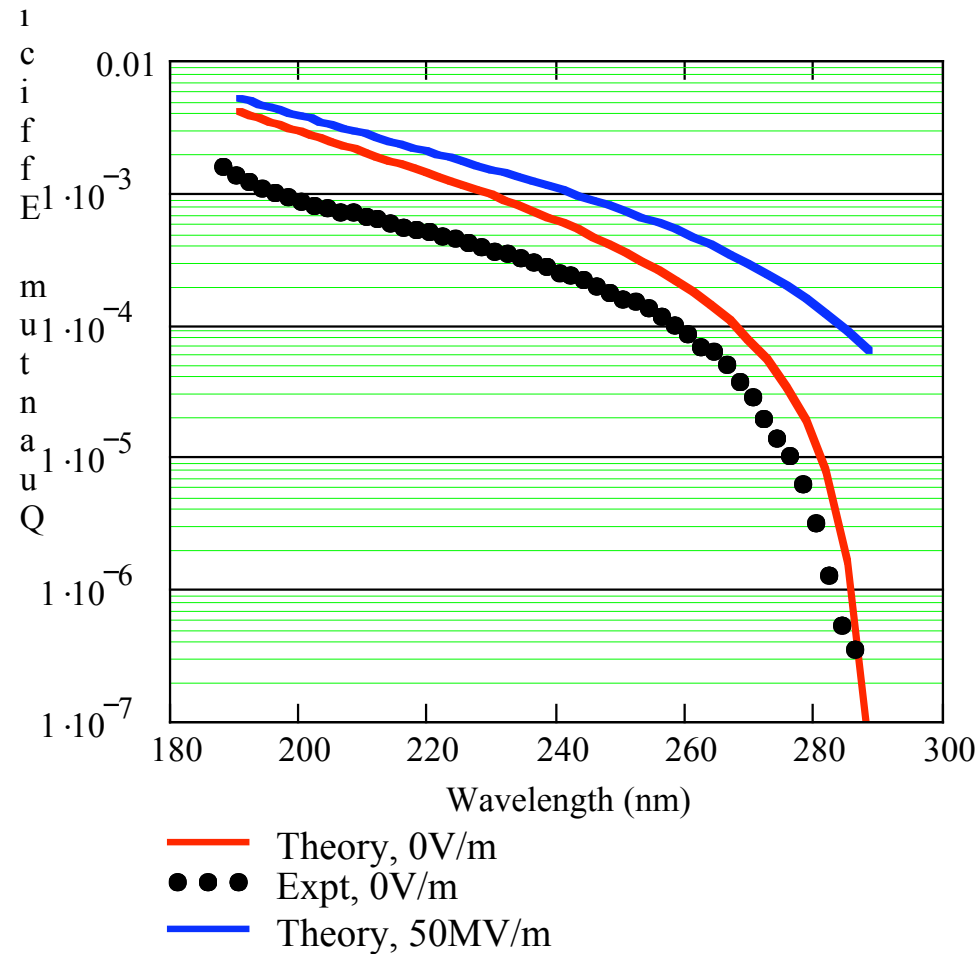
Mean-Square Transverse Momentum

$$\langle p_{\perp}^2 \rangle = \frac{\int_{E_{vac}}^{E_{vac} + \phi_{work} - \phi_{schottky} - \hbar\omega} dE \int_{\cos\theta_{max}}^1 f(\theta) d(\cos\theta) \int_0^{2\pi} d\phi p_{\perp}^2 \text{DOS}_{F-D}}{\int_{E_{vac} + \phi_{work} - \phi_{schottky} - \hbar\omega}^{E_{vac}} dE \int_{\cos\theta_{max}}^1 d(\cos\theta) \int_0^{2\pi} d\phi \text{DOS}_{F-D}}$$

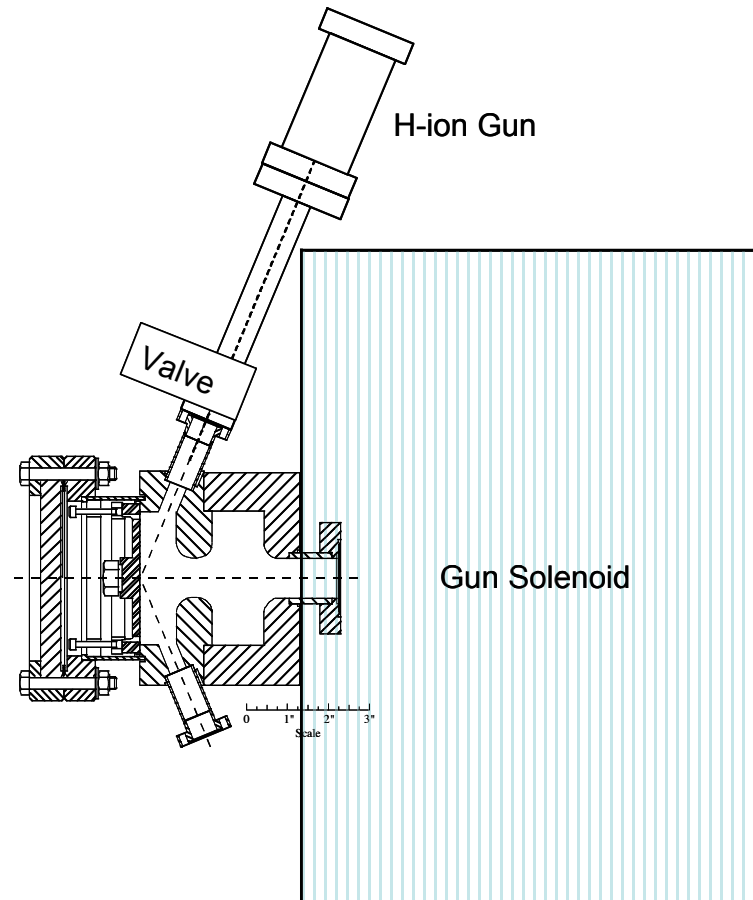
•QE depends upon the reflectivity, the density of states and kinematical filtration

•Discrepancies between this simple model and observations for both QE and “thermal” emittance allow improved understanding of the emission process

Comparison of Measured and Computed QE vs, Wavelength



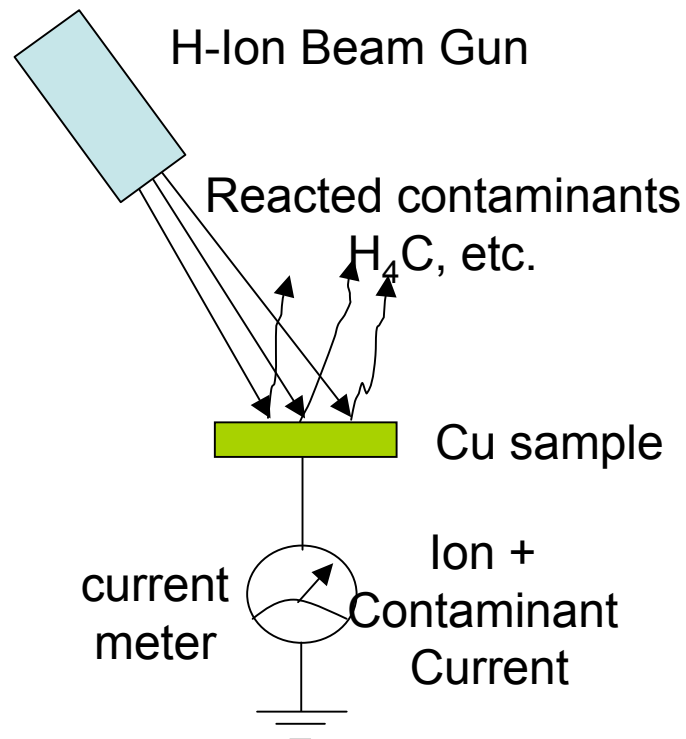
Possible Implementation on S-band Gun



Cathode Cleaners

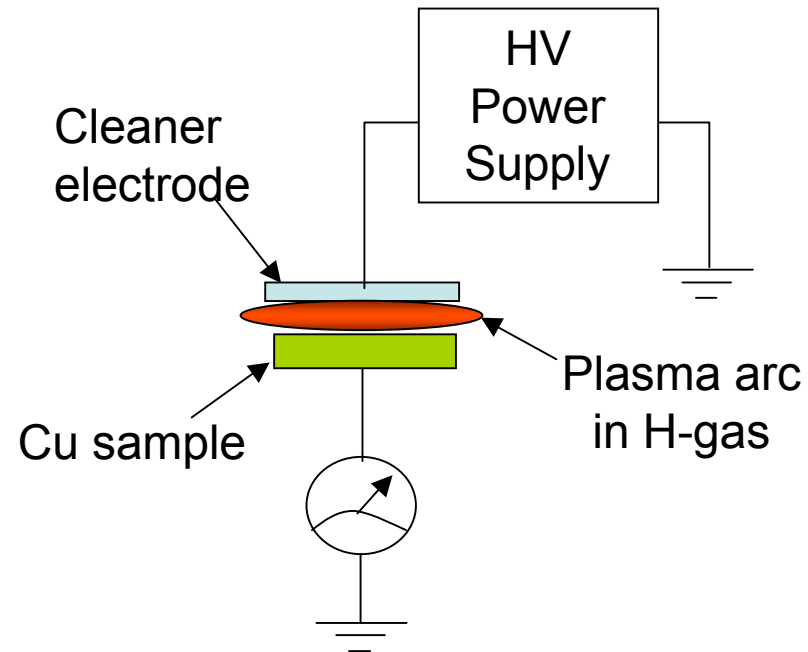
H-Ion Cleaning

(potentially useful for quick in-situ cleaning)



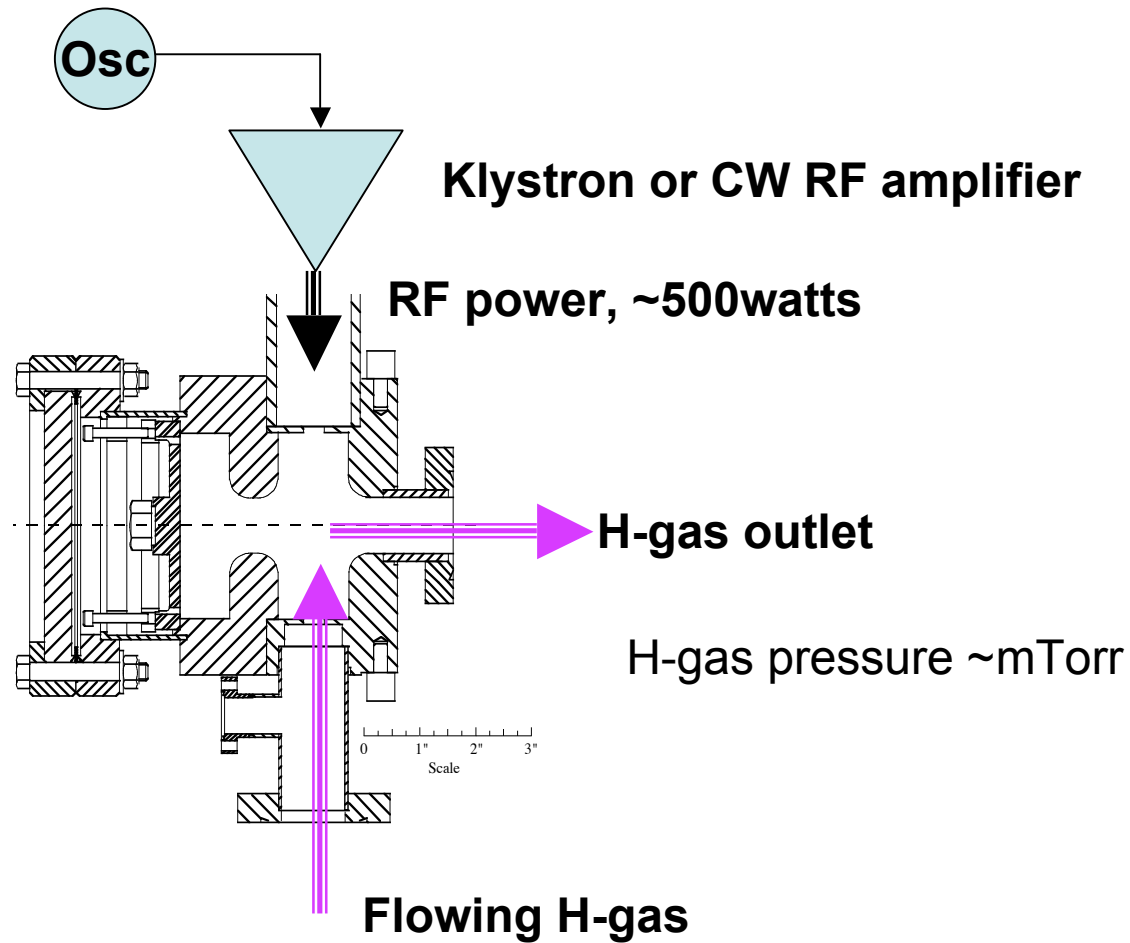
H-Plasma Cleaning

(potentially useful for cleaning entire surface area of cathode before installation)



+ XPS (contamination) and AFM (roughness) characterization of the surface

RF Plasma Cleaning of Gun & Cathode



Summary and Conclusions

H-beam and Plasma Cleaning is a promising technique for producing atomically clean surfaces

Excellent comparison with theory

Plans for implementing on the RF gun is in progress
Cathode processing before installation
In-situ processing